

**IN THE UNITED STATES PATENT AND TRADEMARK OFFICE**

Applicant:	Hong-Jyh Li	Examiner:	Phillip A. Johnston
Serial No.:	10/816,503	Group Art Unit:	2881
Filed:	April 1, 2004	Docket No.:	I331.128.101/2004P51130US
Title:	PLASMA ION IMPLANTATION SYSTEM		

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**AMENDMENT AND RESPONSE**

Mail Stop Amendment  
Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

Dear Sir:

This Amendment and Response is in reply to the Non-Final Office Action mailed June 14, 2007. Please amend the above-identified patent application as follows: